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BIBDATASHEET

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CONFIRMATION NO. 7971

Foreign Priority claimed yes no STATE OR COUNTRY JAPAN SHEETS DRAWING Allowance Acknowledged Examiner's Signature Initials ** 02/06/2004 ** 02/06/2004 STATE OR COUNTRY DRAWING 33 ** OZYGE PRIORITY DRAWING 34 **	DID Data Street										
Masayuki Furuhashi, Kawasaki, JAPAN; Toshifumi Mori, Kawasaki, JAPAN; Young Suk Kim, Kawasaki, JAPAN; Takayuki Ohba, Kawasaki, JAPAN; Ryou Nakamura, Kawasaki, JAPAN; RYOUNG DATA **FOREIGN APPLICATIONS JAPAN 2002-317456 10/31/2002 **FREQUIRED, FOREIGN FILING LICENSE GRANTED **02/06/2004 **Foreign Priority claimed			DATE 10/30/2003						DOCKET NO.		
Toshifumi Mori, Kawasaki, JAPAN; Young Suk Kim, Kawasaki, JAPAN; Takayuki Ohba, Kawasaki, JAPAN; Ryou Nakamura, Kawasaki, JAPAN; **CONTINUING DATA **FOREIGN APPLICATIONS JAPAN 2002-317456 10/31/2002 IF REQUIRED, FOREIGN FILING LICENSE GRANTED **02/06/2004 Foreign Priority claimed yes no Met after Study of Study											
FILING FEE RECEIVED 1248 FILING FEE RECEIVED 1248 Foreign Priority claimed 2 yes no met after whether were including the use of a compound containing silicon and nitrogen to charge/credit DEPOSIT ACCOUNT No for following: FILING FEE RECEIVED 1248	Toshifumi Mori, Kawasaki, JAPAN; Young Suk Kim, Kawasaki, JAPAN; Takayuki Ohba, Kawasaki, JAPAN; Ryou Nakamura, Kawasaki, JAPAN;										
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Foreign Priority claimed	** FOREIGN APPLICATIONS ************************************										
SI USC 119 (a-d) conditions	IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 02/06/2004										
TITLE: Method for fabricating a semiconductor device including the use of a compound containing silicon and nitrogen to form an insulation film of SiN, SiCN or SiOCN FILING FEE RECEIVED 1248 FEES: Authority has been given in Paper to charge/credit DEPOSIT ACCOUNT No for following: FILING FEE RECEIVED 1248 FEES: Authority has been given in Paper to charge/credit DEPOSIT ACCOUNT 1.17 Fees (Processing Ext. of time) 1.18 Fees (Issue) Other	35 USC 119 (a-d) conditions ves no Met after met Verified and				COUNTRY	DRA	DRAWING CLA		VIS	CLAIMS	
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